## ABSTRACT OF THE DISCLOSURE

A system and method for canceling disturbance in a MEMS device. The system 200 includes a MEMS device 203, which may include a substrate 205 and a plurality of individually movable MEMS elements 203-1 through 203-N, and a control assembly 207. The optical system 200 may be utilized in and/or form a portion of any optical apparatus employing an array of MEMS devices. The control assembly 207 uses feed-forward control signals to cancel disturbance in the MEMS device 203, and more particularly, to cancel disturbance in the non-switched or static mirrors of the MEMS device 203 caused by switched or moving mirrors.

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